

O I P E

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INFORMATION

Notice of References Cited

DISCLOSURE STATEMENT

Application/Control No.

09/954,287 10/666,120

Applicant(s)/Patent Under
Reexamination
NIKOONAHAD ET AL

Examiner

Richard A Rosenberger

Art Unit

2877

Page 1 of 1

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	C	US-			
	D	US-			
	E	US-			
	F	US-			
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*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
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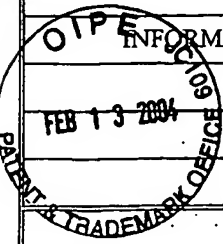
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Part of Paper No. 12

1449

U.S. Department of Commerce, Patent and Trademark Office				Atty Docket No.		Serial No.	
				M-10575-2C US		09/760,558 10/666,120	
 INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)				Applicant(s)			
				MEHRDAD NIKOONAHAD ET AL.			
				Filing Date		Group	
				January 16, 2001		2877	
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<i>m</i>	AB	5,189,481	2/23/93	Jann et al.	356	73	
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	AL						Yes No
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	AQ	ISOMET Corporation Specification for LS-55 V Acousto Optic Deflector/AOT, 4 pages					
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Examiner	<i>RAD</i>		Date Considered <i>3/11/04</i>				
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.							

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	Examiner Richard Rosenberger	Art Unit 2877	Page 1 of 1

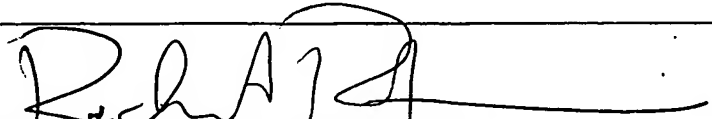
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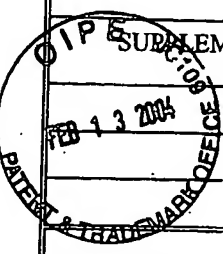
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT				TNCR.001US4		10/666,120		
				Applicant(s)		Conf. No.		
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					September 11, 2001		2877	

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	B2	H5-332946	12/17/93	Japan			Yes	
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<i>[Signature]</i>	B7	62-274633	11/1987	Japan			Yes	
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						Applicant(s)		10/1066, 1.10	
						MERHDAD NIKOONAHAD ET AL.			
						Filing Date		Group	
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